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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re PATENT APPLICATION of : Attorney Docket No. OKI.614  
Yasuhiro Yamamoto et al. : Examiner: Young, Christopher G  
Application No.: 10/761,215 : Group Art Unit: 1756  
Filed: January 22, 2004 : Confirmation No. 2755  
For: FLARE MEASURING MASK AND FLARE MEASURING METHOD OF SEMICONDUCTOR ALIGNER

**LETTER REQUESTING ACKNOWLEDGEMENT OF CLAIM OF PRIORITY**

U.S. Patent and Trademark Office  
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Date: November 21, 2006

Sir:

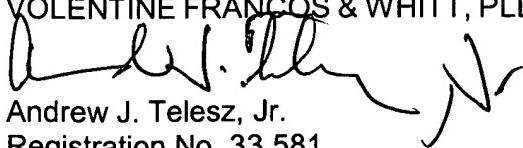
A certified copy of Japanese priority application no. 2003-371747 was filed on November 13, 2006, in connection with the above identified application. Japanese priority application no. 2003-371747 has been entered into the image file wrapper of the present application at the U.S. Patent Office website.

**The Examiner is respectfully requested to confirm that the Claim for Priority under 35 U.S.C. 119 is thus complete in the present application.**

In the event that there are any outstanding matters remaining in the present application, please contact Andrew J. Telesz, Jr. (Reg. No. 33,581) at (571) 283-0720 in the Washington, D.C. area, to discuss these matters.

Respectfully submitted,

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